Amendment and Response Under 37 C.F.R. 1.116

Applicant: Josef Böck et al. Serial No.: 10/521,106 Filed: September 13, 2005

Docket No.: I435.121.101/12307US Title: BIPOLAR TRANSISTOR

## IN THE CLAIMS

Please cancel claims 25-26.

Please add claim 33.

Please amend claims 9, 24 and 27 as follows:

- 1-8 (Cancelled)
- 9. (Previously Presented) A bipolar transistor comprising:
  an emitter area which can be contacted electrically via an emitter electrode;
  a base area which can be contacted electrically via a base electrode;
  a collector area which can be contacted electrically via a collector electrode; and wherein at least one electrode of the emitter electrode, base electrode and collector electrode is a polysilicon layer, into which doping is inserted and impurity atoms are inserted, wherein the inserting of the impurity atoms causes a high density of vacancies in the polysilicon layer, the density in the range of about 10<sup>19</sup> to 10<sup>21</sup> cm<sup>-3</sup>, and wherein the impurity atoms are C, P or Ar atoms and wherein the combination of the inserted doping and inserted impurity atoms is such that the electrode resistance is reduced.

10.-11. (Cancelled)

- 12. (Previously Presented) The transistor of claim 9, comprising wherein the polysilicon layer is doped with boron atoms.
- 13. (Previously Presented) The transistor of claim 12, comprising wherein the concentration of the boron atoms is greater than  $5 \times 10^{20}$  cm<sup>-3</sup>.
- 14. (Previously Presented) The transistor of claim 9, comprising wherein the at least one electrode consists of polycrystalline silicon-germanium.

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- 15. (Previously Presented) The transistor of claim 9, comprising wherein the at least one electrode is the base electrode.
- 16. (Previously Presented) The transistor of claim 9, comprising wherein the bipolar transistor is a self-aligned bipolar transistor.

## 17.-23 (Cancelled)

- 24. (Previously Presented) A bipolar transistor comprising:
  an emitter area which can be contacted electrically via an emitter electrode;
  a base area which can be contacted electrically via a base electrode;
  a collector area which can be contacted electrically via a collector electrode; and wherein at least one electrode of the emitter electrode, base electrode and collector electrode is a polysilicon layer doped with boron atoms, into which impurity atoms, which cause a high density of vacancies in the polysilicon layer, are inserted, wherein the impurity atoms are
  C, P or Ar atoms;
- , and wherein the density of the impurity atoms in the polysilicon layer is in the range of about  $10^{19}$  to  $10^{21}$  cm<sup>-3</sup>; and

wherein the concentration of the boron atoms is greater than 5 x 10<sup>20</sup> cm<sup>-3</sup>.

- 25. (Cancelled)
- 26. (Cancelled)
- 27. (Previously Presented) The transistor of claim 2624, comprising wherein the at least one electrode consists of polycrystalline silicon-germanium.

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- 28. (Previously Presented) The transistor of claim 27, comprising wherein the at least one electrode is the base electrode.
- 29. (Previously Presented) The transistor of claim 28, comprising wherein the bipolar transistor is a self-aligned bipolar transistor.

30.-32 (Cancelled)

33. (New) A bipolar transistor comprising:
an emitter area which can be contacted electrically via an emitter electrode;
a base area which can be contacted electrically via a base electrode;

a collector area which can be contacted electrically via a collector electrode;

wherein a polysilicon layer is used as the base electrode;

wherein the extrinsic base resistance of the base electrode is reduced by inserting impurity C atoms into the polysilicon layer, thereby causes a high density of vacancies in the polysilicon layer; and

wherein doping is inserted in the polysilicon layer.